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pproved for use through 10/31/99. OMB 0651-0031 Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE **COMPLETE IF KNOWN** 09/888,084 **Application Number** substitute for form 1449A/PTO 8101 **ANFORMATION DISCLOSURE Confirmation Number** June 21, 2001 ATEMENT BY APPLICANT Filing Date Whonchee Lee First Named Inventor se as many sheets as necessary) 3723 Group Art Unit Examiner Name 108298515US1 of 1 Attorney Docket No. 1 U.S. PATENT DOCUMENTS Pages, Columns, Lines, Date of Publication of Cited *EXAMINER U.S. Patent Document Name of Patentee or Applicant Where Relevant Passages or of Cited Document INITIALS NUMBER Kind Code Document Relevant Figures Appear (if known) 1/23/01 PVN AA 6,176,992 ~ Talieh 7/27/99 AΒ 5,930,699/ **Bhatia** AC Uzoh et al. 9/15/98 5,807,165~ ΑD AE AF AG AH ΑI AJ FOREIGN PATENT DOCUMENTS Pages, Columns, Lines, Where Date of Publication of *EXAMINER Foreign Patent Document Cite Name of Patentee or Applicant Relevant Passages or Relevant T INITIALS No. Kind Code of Cited Document Cited Document Figures Appear Office Number (if known) ΑK AL AM AN

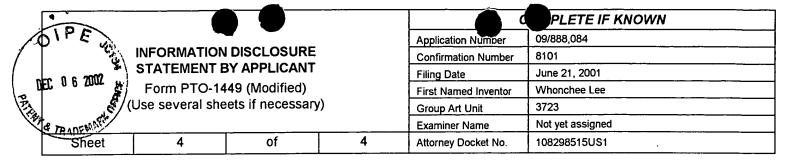
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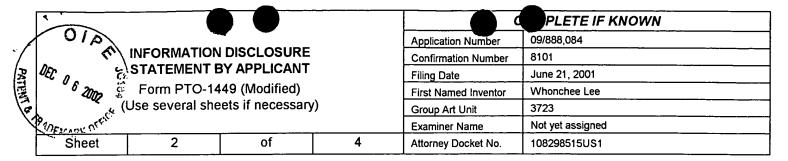
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PLETE IF KNOWN 09/888,084 Application Number INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
Form PTO-1449 (Modified)
Use several sheets if necessary) 8101 Confirmation Number June 21, 2001 Filing Date Whonchee Lee First Named Inventor 3723 Group Art Unit A TH THE WALL Not yet assigned **Examiner Name** 3 of 4 Sheet 108298515US1 Attorney Docket No.

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1		7/Earm DTO 1/	49 (Modified)		First Named Inventor	Whonchee Lee
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	Sheet	1	of	4	Attorney Docket No.	108298515US1

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S MAIL LABEL NO.: EV 139295330 US COMPLETE IF KNOWN Application Number 09/888,084 **INFORMATION DISCLOSURE** Confirmation Number 8101 STATEMENT BY APPLICANT Filing Date June 21, 2001 Form PTO-1449 (Modified) First Named Inventor Whonchee Lee (Use several sheets if necessary) 3723 Group Art Unit **Examiner Name** Dung V. Nguyen of Sheet Attorney Docket No. 108298515US3

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Application Number	09/888,084
Confirmation Number	8101
Filing Date	June 21, 2001
First Named Inventor	Whonchee Lee
Group Art Unit	3723
Examiner Name	Dung V. Nguyen
Attorney Docket No.	108298515US1

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Examiner Name	Dung V. Nguyen						
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